

1. Record Nr.	UNINA9910784722203321
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Titolo	Analysis of piezoelectric devices [[electronic resource] /] / Jiashi Yang
Pubbl/distr/stampa	Hackensack, NJ, : World Scientific, c2006
ISBN	1-281-37307-9 9786611373078 981-277-318-5
Descrizione fisica	xv, 520 p. : ill
Disciplina	537/.2446
Soggetti	Piezoelectric devices - Mathematical models
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Title from title screen.
Nota di bibliografia	Includes bibliographical references (p. 491-500) and index.
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